Express Mail Label No.	Dated:	

Docket No.: 20110/0200839-US0

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Kazuo Kasai et al.

Application No.: Not Yet Assigned

Confirmation No.:

Filed: Concurrently Herewith

Art Unit: N/A

For:

SILICON SUBSTRATE ETCHING METHOD Examiner: Not Yet Assigned

AND ETCHING APPARATUS

INFORMATION DISCLOSURE STATEMENT (IDS)

MS Patent Application Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 CFR 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO/SB/08. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement accompanies the new patent application submitted herewith.

Pursuant to the Notice issued by the United States Patent and Trademark Office dated July 11, 2003 waiving the requirements of 37 CFR 1.98(a)(2)(i), copies of United States Patents on PTO/SB/0A are not submitted.

Application No.: Not Yet Assigned 2 Docket No.: 20110/0200839-US0

Citations BA and BC are not in the English language. In accordance with 1.98(c), Applicants state:

The requirement for concise explanation of relevance of Citations BA and BC is satisfied by the attached translation of the abstract (see MPEP § 609 A(3)). Also enclosed is an English language copy of a Search Report from a foreign patent office, issued in a counterpart application.

In accordance with 37 CFR 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR 1.56(a) exists. In accordance with 37 CFR 1.97(h), the filing of this Information Disclosure statement shall not be construed to be an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

It is submitted that the Information Disclosure Statement is in compliance with 37 CFR 1.98 and the Examiner is respectfully requested to consider the listed references.

The Commissioner is authorized to charge any deficiency of up to \$300.00 or credit any excess in this fee to Deposit Account No. 04-0100.

Dated: March 29, 2004

Respectfully submitted

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PTO/SB/08a/b (08-03)

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Substitute for form 1449A/B/PTO		Complete if Known			
000			Application Number	Not Yet Assigned	
INFORMATION DISCLOSURE			CLOSURE	Filing Date	Concurrently Herewith
STATEMENT BY APPLICANT		First Named Inventor	Kazuo Kasai		
_	(Use as many sheets as necessary)			Art Unit	N/A
				Examiner Name	Not Yet Assigned
Sheet	1	of	1	Attorney Docket Number	20110/0200839-US0

			U.S. PA	TENT DOCUMENTS	
Examiner Cite Initials* No.1	Document Number	Publication Date	Name of Patentee or	Pages, Columns, Lines, Where Relevant Passages or Relevant	
		Number-Kind Code ² (if known)	id Code ² (if known) MM-DD-YYYY	Applicant of Cited Document	Figures Appear
	AA	US-4,579,623-A1	04-01-1986	Hitachi, Ltd.	
	AB	US-4,795,529-A1	01-03-1989	Hitachi, Ltd.	

		FOREI	GN PATENT	DOCUMENTS		
Examiner Initials*	Cite No.¹	Foreign Patent Document Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
., .	ВА	JP-61-256725-A1	11-14-1986	Hitachi, Ltd.		1
-	ВВ	EP-0 822 582-A2	02-08-1998	Surface Technology Systems, Ltd.		
	вс	JP-10-135192-A1	05-22-1998	Surface Technology Systems Ltd.		1

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. *Applicant's unique citation designation number (optional). *See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. *Senter Office that issued the document, by the two-letter code (WIPO Standard ST.3). *For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. *Skind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. *Applicant is to place a check mark here if English language Translation is attached.

		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
	CA	Patent Abstracts of Japan for JP61-256725 published on November 14, 1986.	
	СВ	Patent Abstracts of Japan for JP10-135192 published on May 22, 1998.	

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

{W:\201	Date	
	Considered	
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¹Applicant's unique citation designation number (optional). ²Applicant is to place a check mark here if English language Translation is attached.